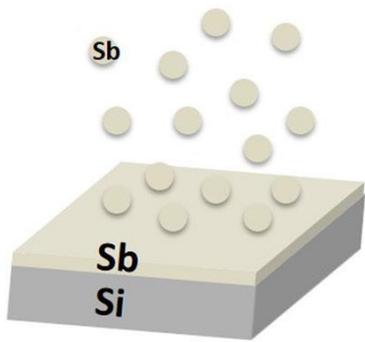


# Recent update on ANL MCP-PMT

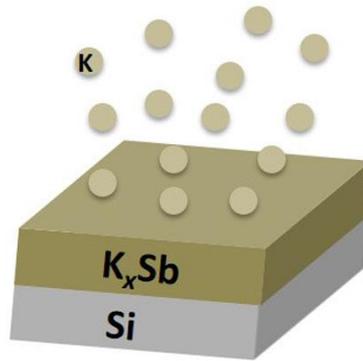
*Junqi Xie on behalf of the detector R&D group*

*Argonne National Laboratory, Argonne, IL*

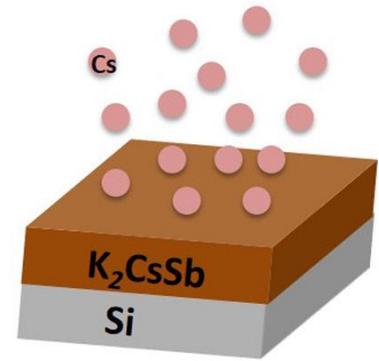
*Email: [jxie@anl.gov](mailto:jxie@anl.gov)*



(a)



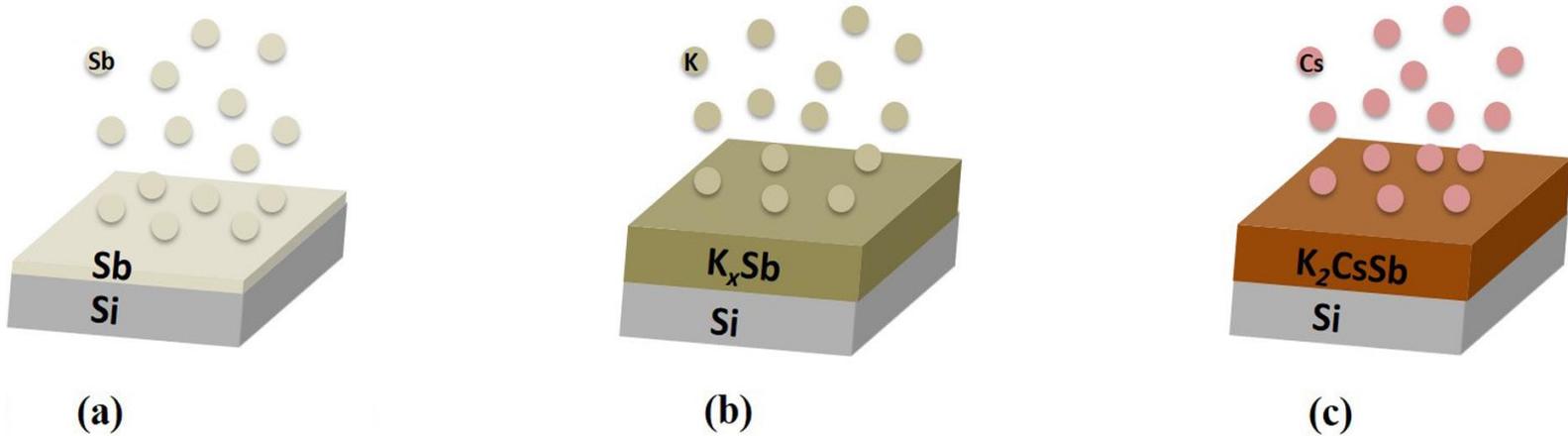
(b)



(c)



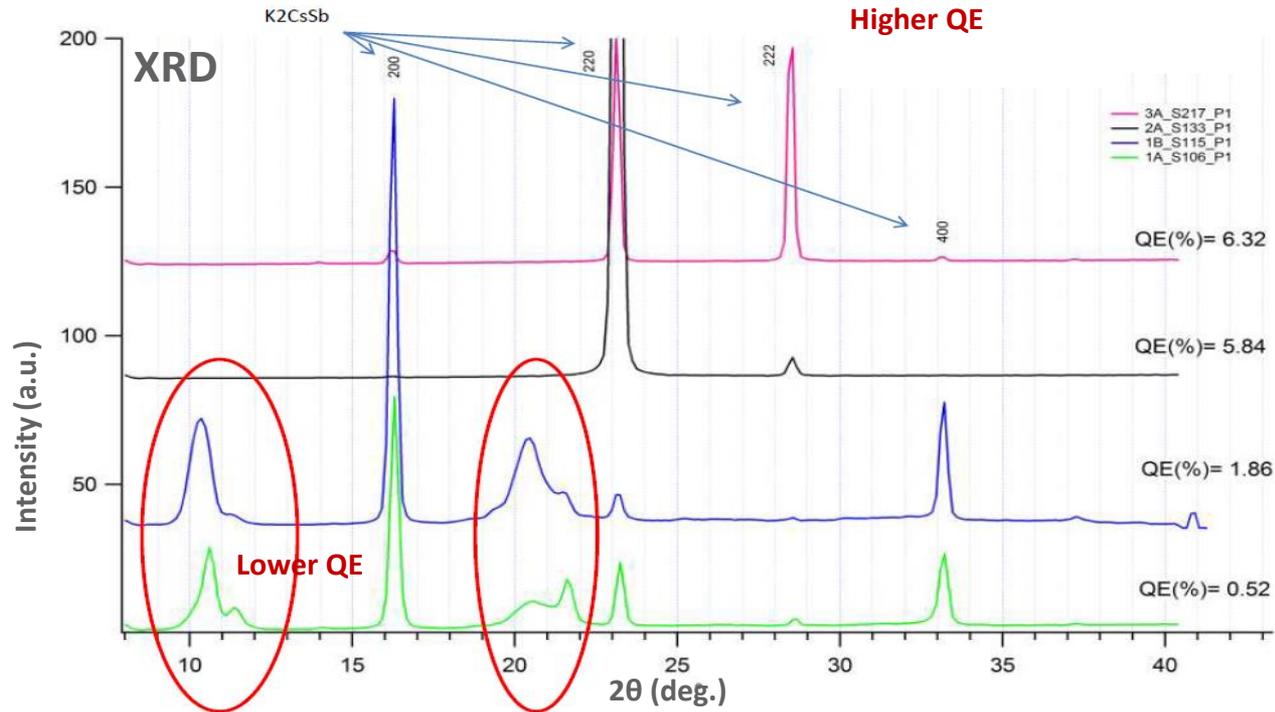
# Traditional diffusion deposition process



Schematic diagram shows the diffusion process of the  $K_2CsSb$  photocathode: (a) Sb thin film deposition; (b) K diffusion forming a  $K_xSb$  compound; and (c) Cs diffusion forming a  $K_2CsSb$  photocathode.



# X-ray analysis results



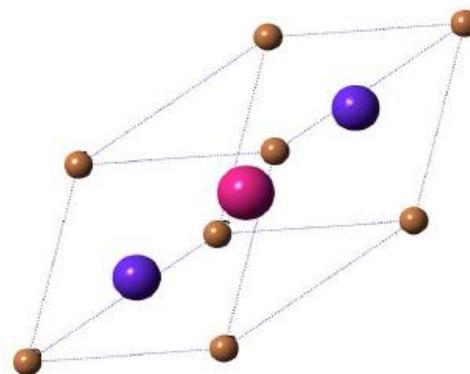
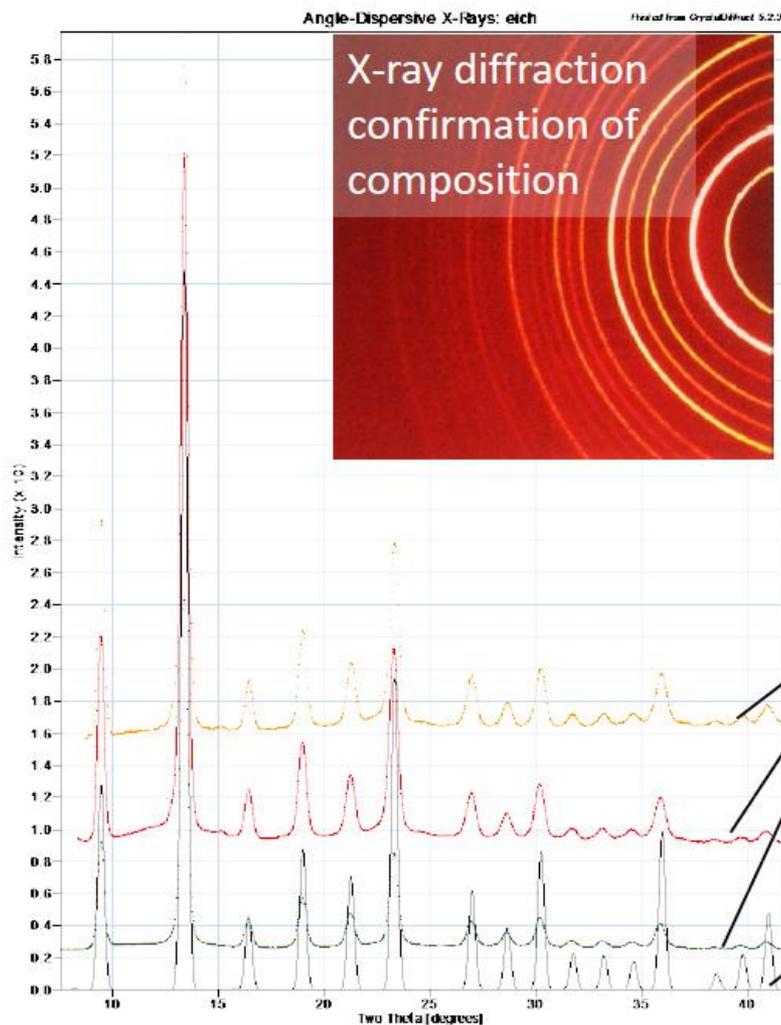
- Stoichiometry was not able to control precisely
- Photocathodes display various QE values (low and high)
- High QE cathode exhibits **single  $K_2CsSb$  compound**, low QE cathodes exhibit mixture of different compositions.



**New think - Synthesize the compound first, then do the deposition**



# The Breakthrough Chemical Synthesis



As-synthesized  $K_2CsSb$  compound

A good match !!!

Calculated diffraction data for the desired cubic  $K_2CsSb$

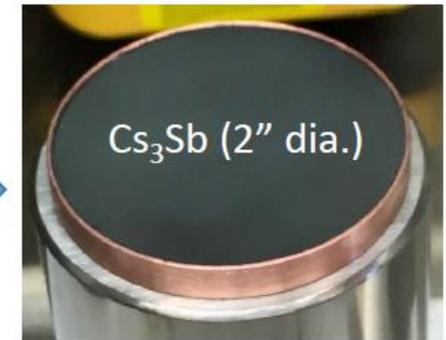


- > 95 % pure phase
- Nanocrystalline Material (15-30 nm)

$K_2CsSb$  – the predicted structure is confirmed experimentally



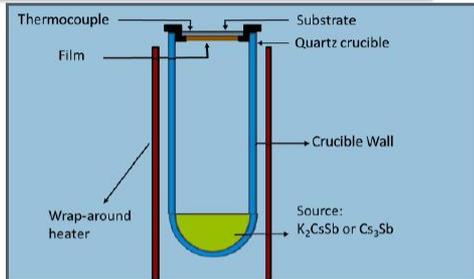
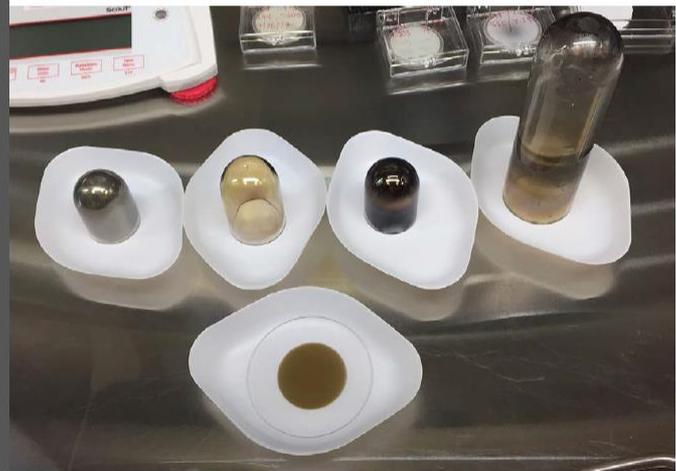
# Solid State Synthesis



Challenge: The reaction chemistry is highly exothermic and the product is reactive to ambient moisture

Solution: Solid state synthesis performed in a controlled environment

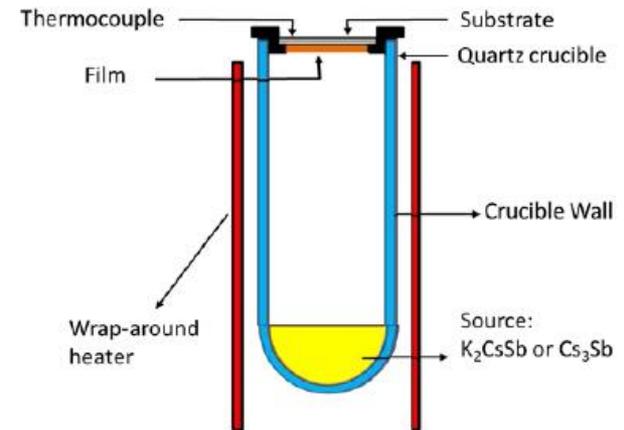
# Evaporation Process



Hot Wall Evaporation



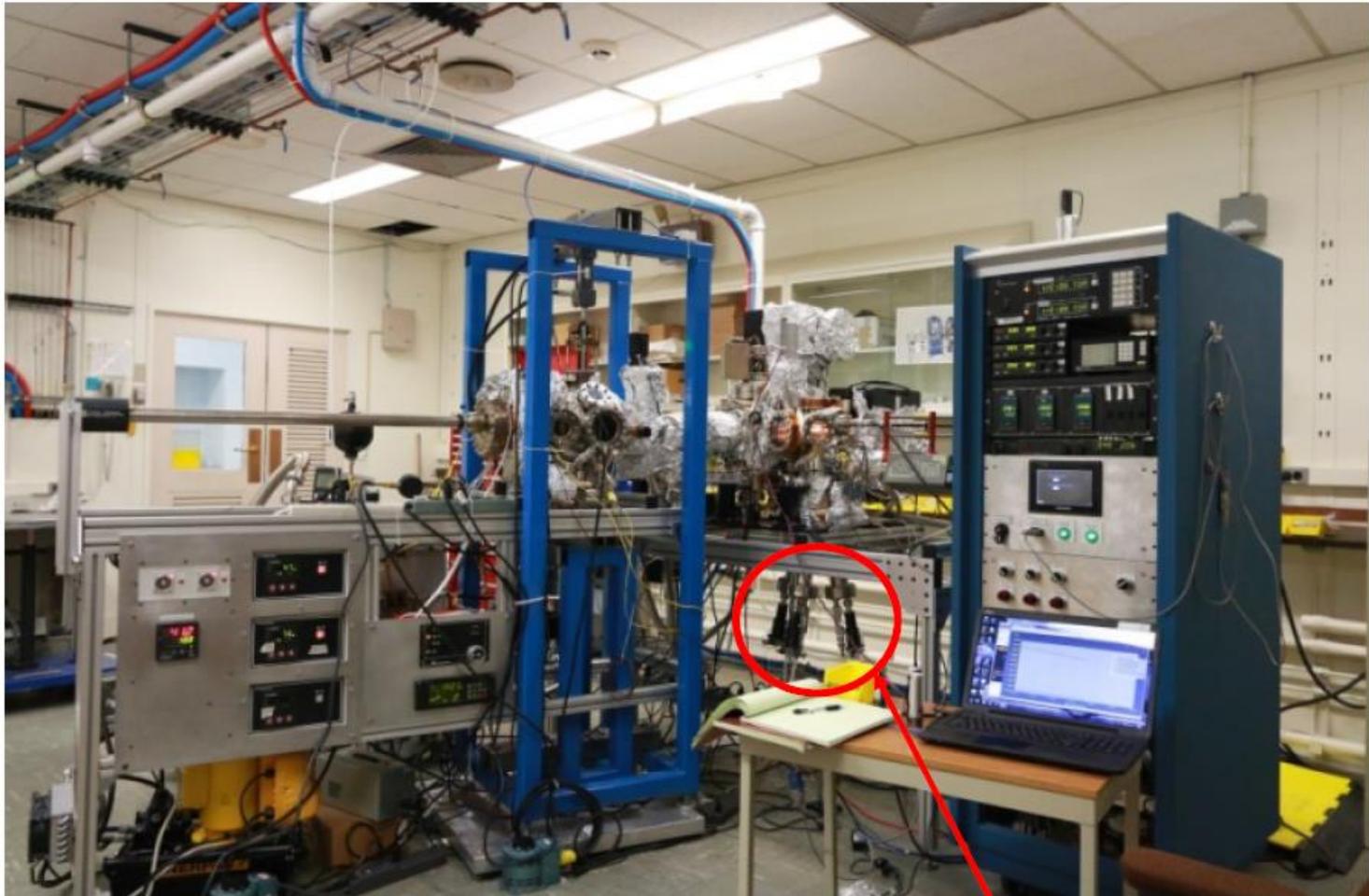
# Evaporation Process



Hot Wall Evaporation



# Photodetector fabrication facility



Modification is required here



# Task: Modified design for sources

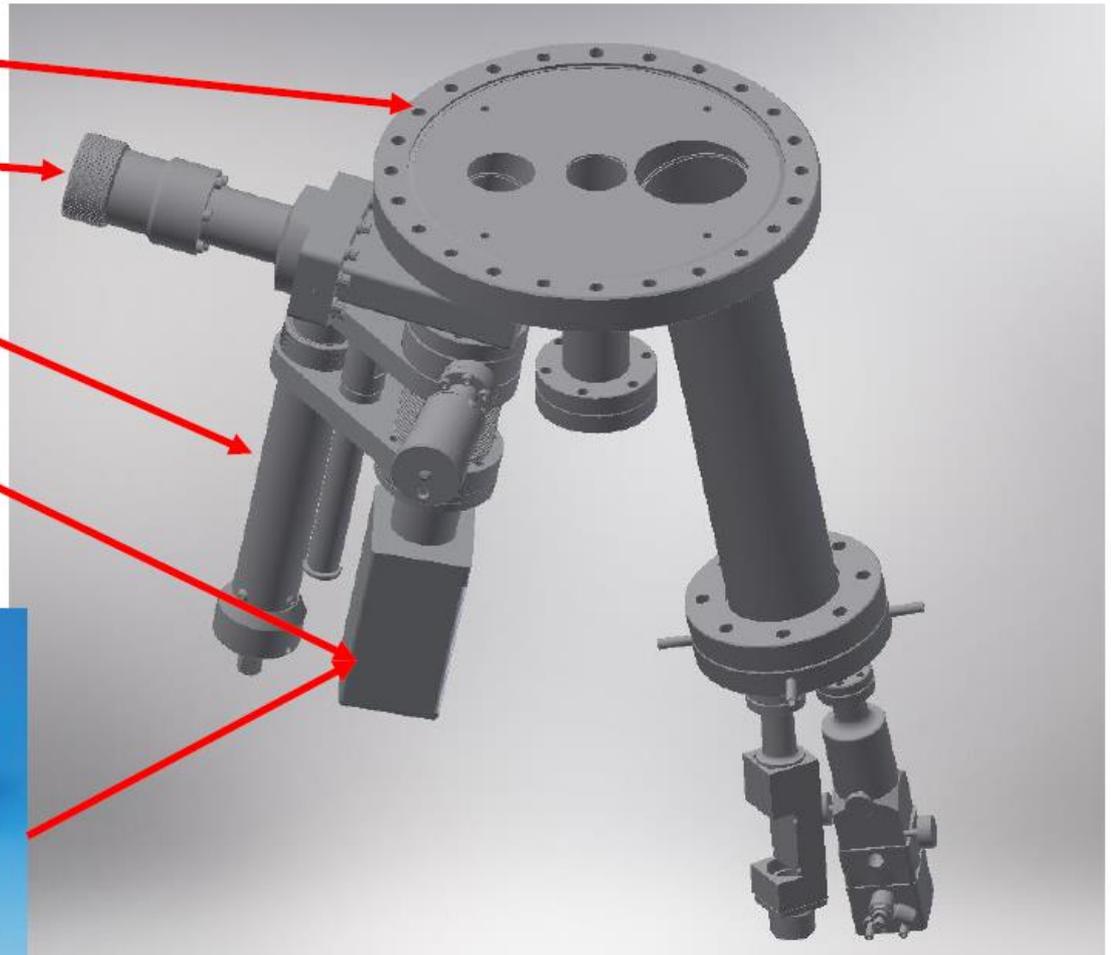
The new design does not use an effusion cell, use a direct thermal evaporation source to evaporate the bulk material, easier handling.

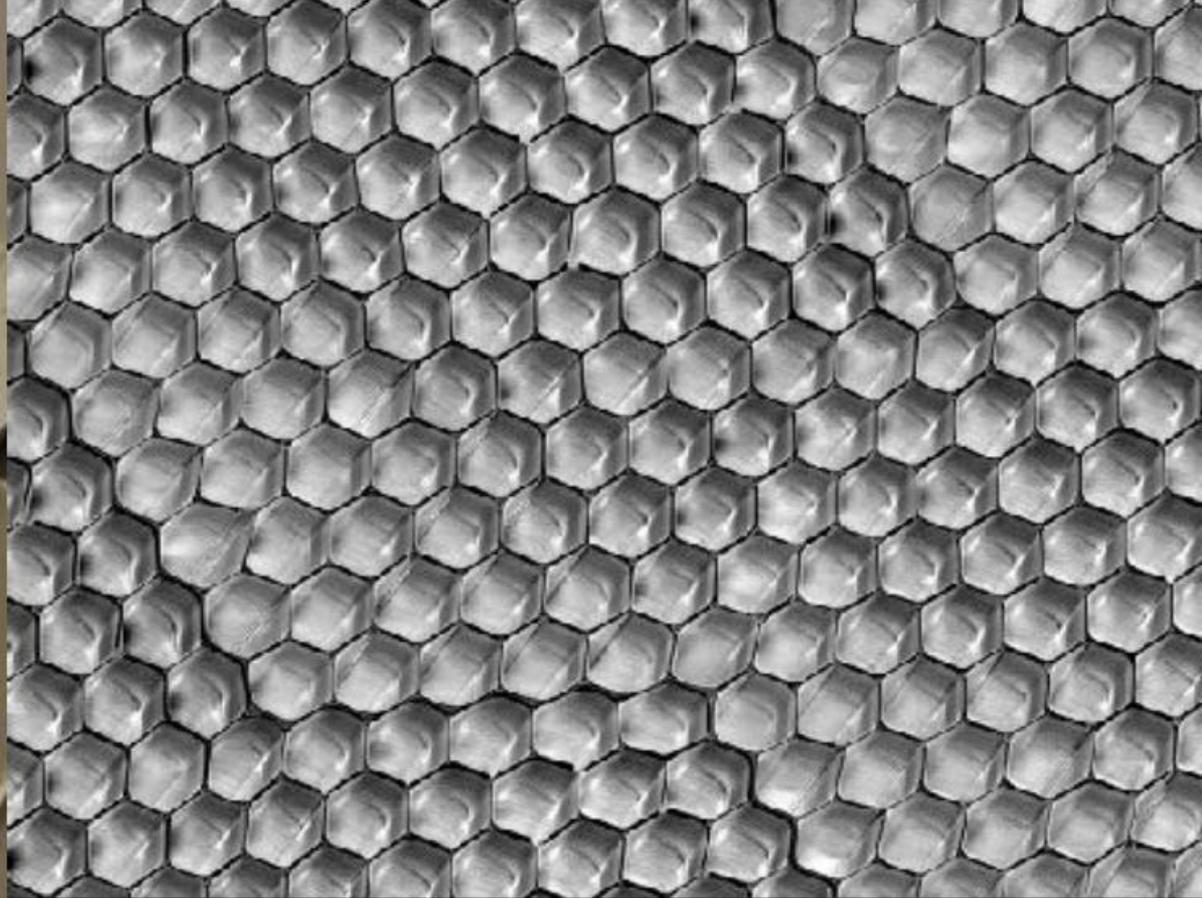
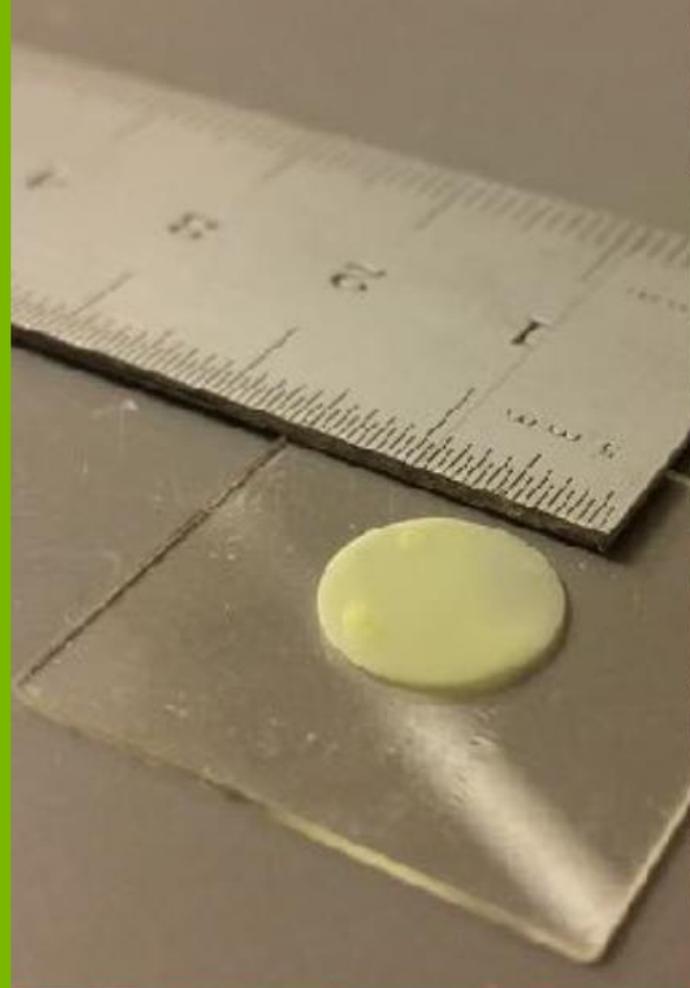
Source flange

Gate valve

Single axis stage

Evaporation source





SED 5.0kV WD11mm P.C.50 HV x500  
Argonne Natl Lab

50 $\mu$ m

0048

Nov 1

## 3D PRINTING OF CAPILLARY ARRAYS FOR MICROCHANNEL PLATES

# SO, HOW DOES ONE PRINT AN MCP?

- Use Two Photon Polymerization (TPP) of photoresist to make structure
  - First shown by Maruo & Kawata “Two-photon absorbed near-infrared photopolymerization for three-dimensional microfabrication”, J. MEM. Sys **7**, 411 (1998).
  - Infrared laser (780nm) focused to small spot where power is sufficient to produce TPP. Resolution is  $\sim 0.1\text{-}1\mu\text{m}$ .
    - ▶ Varying laser power ranges effect from no polymerization, to useful polymerization, to blistering

- Write the structure by moving laser from point-to-point

laser draw as shown  
by monitor camera

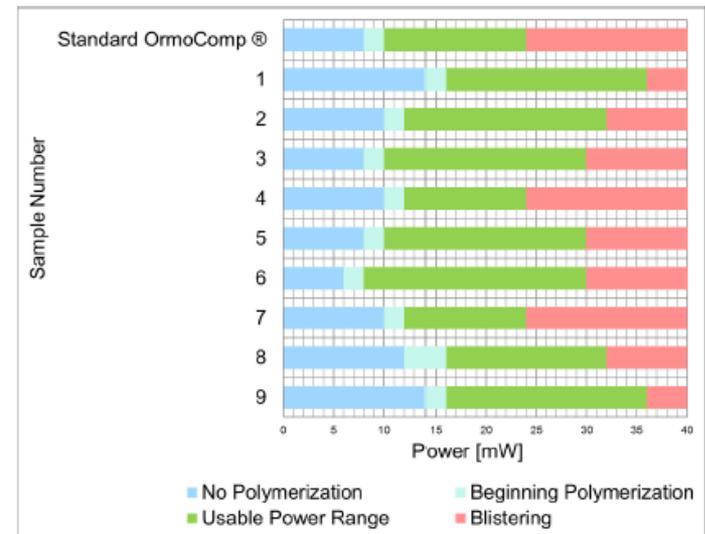
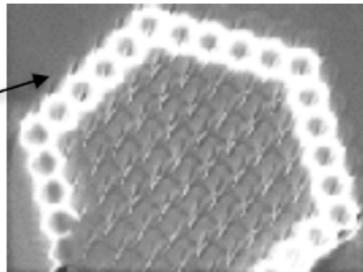


figure credit: Hamisch & Schmitt, SPIE (2017)

- Complete process with developer and UV illumination
- 3D TPP printers commercially available
  - ▶ We use Nanoscribe Photonic Professional (GT)

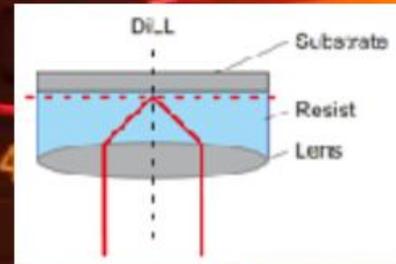
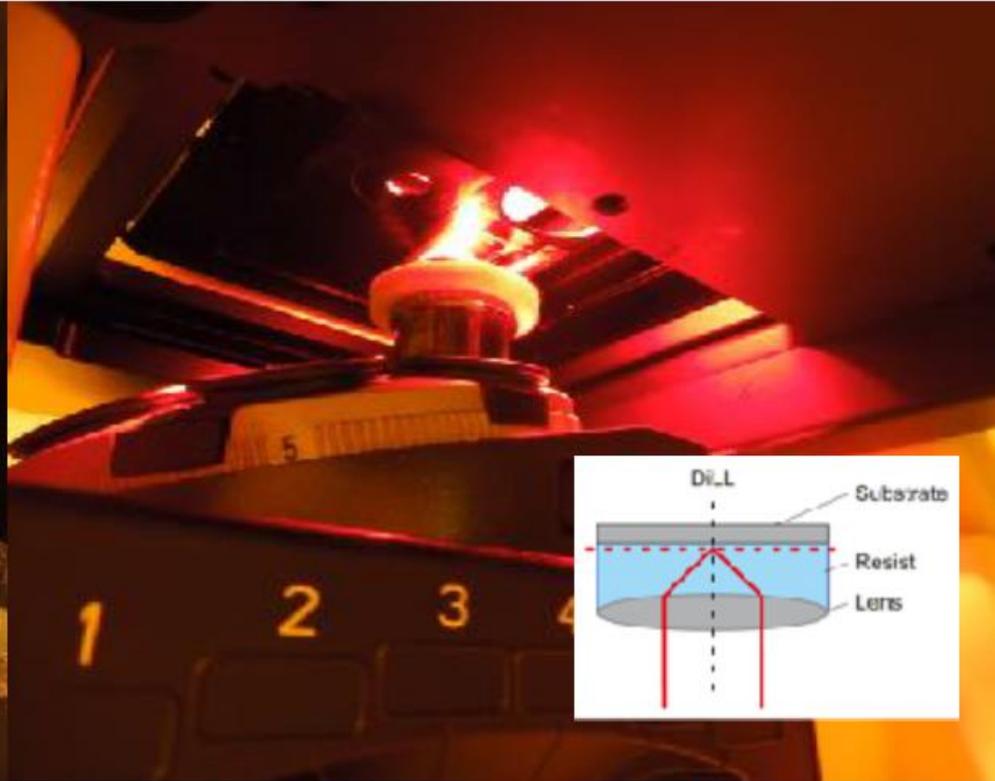


# NANOSCRIBE 3D PRINTER SPECIFICS



Printer is “table-top” device consisting of

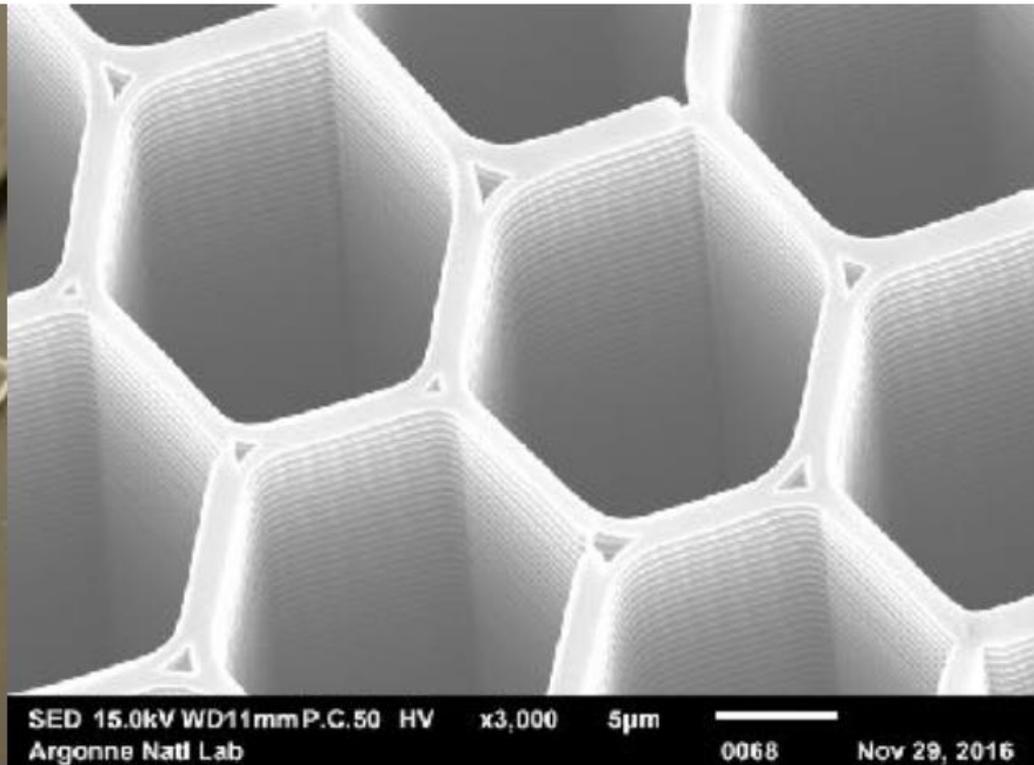
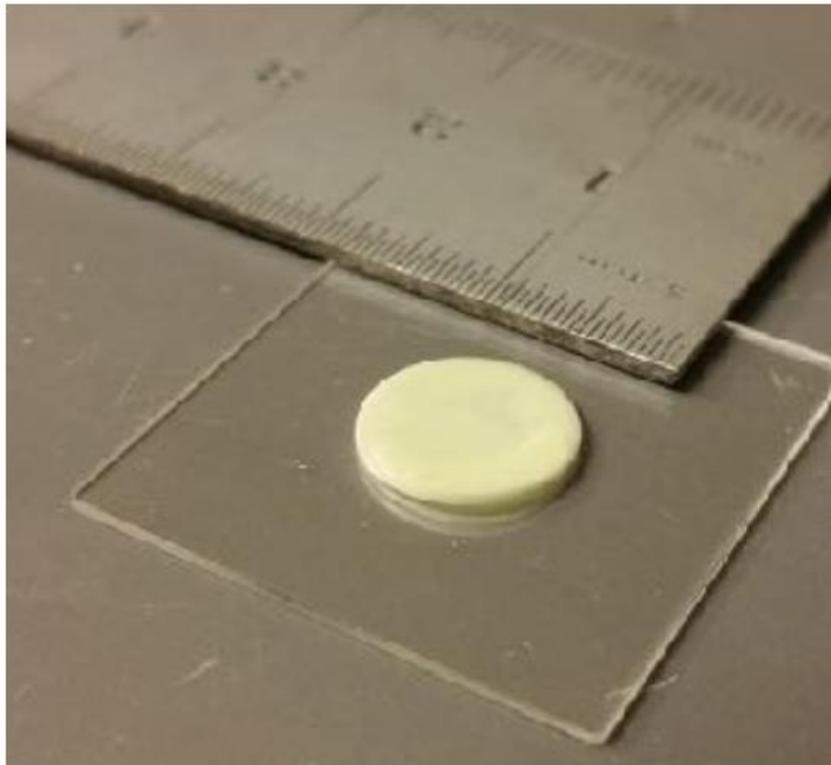
- Floating optical table
- Laser and focussing optics
- Microscope and autofocus system
- Motorized stage: stage (cm movement), piezo (300 $\mu$ m), galvo (100nm-400 $\mu$ m)



Photoresist applied to glass plate which is inverted and inserted into stage.

Microscope lens is dipped into photoresist to focus laser spot onto print voxel. Dip-In Laser Lithography (DiLL)  
Printing starts at just inside glass/resist interface to adhere structure to glass

# 1CM CAPILLARY ARRAY WITH HEXAGONAL PORES



## Completed capillary array

- Resist stabilized after print with developer
- Wash with isopropanol
- Exposure to UV lamp for 15 minutes completes any polymerization

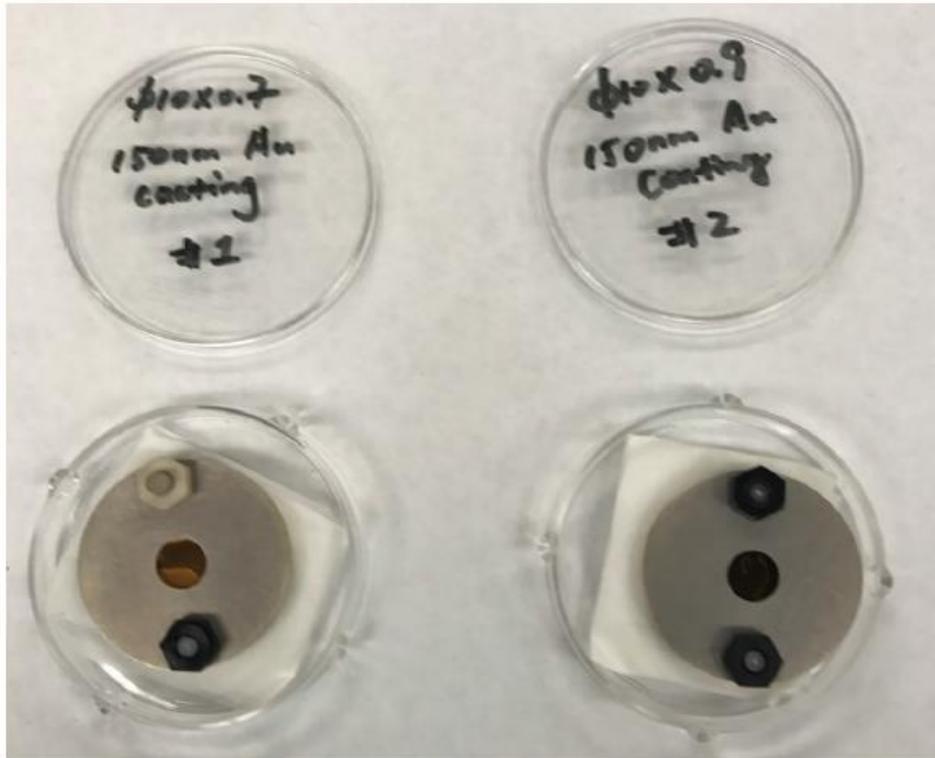
## SEM image of earlier capillary array

- Laser write speed too fast causes breaks in structure at vertices

Overall size of capillary array that can be printed **currently** limited by writing speed: 1cm x 0.9mm array takes 39 hours

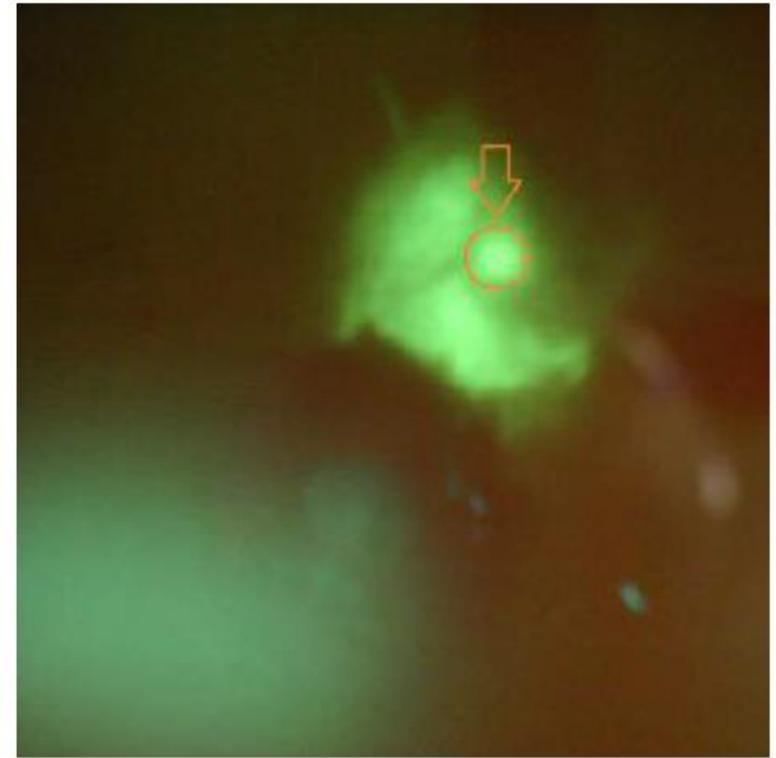


# FUNCTIONALIZATION OF 3D PRINTED MCP VIA ALD AND DEMONSTRATION OF GAIN PRODUCTION



1cm MCP with 10 $\mu$ m pores after ALD coating

- Resistance  $\sim 2\text{G}\Omega$ ; high but usable
- SEE layer —  $\text{Al}_2\text{O}_3$



1cm MCP image in phosphor chamber

- Illuminated with UV lamp to ionize electrode
- Gain produced in 1cm MCP further amplified by second 8" MCP

